

SENTECH Thin Film Metrology Workshop

Thin Film Metrology Workshop – Day 1

Date: 15 October 2025

Host: SENTECH Gesellschaft für Sensortechnik mbH,
Konrad-Zuse-Bogen 13, 82152 Krailling

Location: SENTECH Instruments GmbH,
Entrance: Johann-Hittorf-Str./James-Franck-Str., 12489 Berlin-Adlershof

Networking dinner: Il Porto, Semmelweisstraße 104a, 12524 Berlin

Please note:

Your own laptop will be required for this workshop. Please ensure to bring one with you! A special license for the SpectraRay/4 software will be provided by SENTECH Instruments GmbH for the duration of the workshop.

WORKSHOP PROGRAM:

Pos.	Time	Talk
1.	9:00	Welcome to SENTECH Instruments GmbH Friedrich P. Witek, SENTECH GmbH, Krailling and SENTECH Instruments GmbH, Berlin
2.	9:15	Introduction to Spectroscopic Ellipsometry Raphael Präg, SENTECH Instruments GmbH, Berlin
3.	9:45	Ellipsometric Workflow and Operation of SpectraRay/4 Elena Ermilova, SENTECH Instruments GmbH, Berlin
	10:30	Coffee Break
4.	11:00	Understanding Material Dispersion in Ellipsometry Sven Peters, SENTECH Instruments GmbH, Berlin
	12:00	Lunch Break / Installation of the Software
5.	13:20	Exercise: Iterative Model Improvement
	15:00	Coffee Break
6.	15:30	Exercise: Advanced Optical Modeling
7.	17:20	Automating Ellipsometry: Scripting for Smarter Measurements Uwe Richter, SENTECH Instruments GmbH, Berlin
	18:20	End of Workshop – Day 1
	19:00	Networking dinner at Il Porto

Thin Film Metrology Workshop – Day 2

Date: 16 October 2025

Host: SENTECH Gesellschaft für Sensortechnik mbH,
Konrad-Zuse-Bogen 13, 82152 Krailling

Location: SENTECH Instruments GmbH,
Entrance: Johann-Hittorf-Str./James-Franck-Str., 12489 Berlin-Adlershof

Please take care not to bring confidential samples or samples under NDA for the Workshop, as these measurements are performed in groups.

WORKSHOP PROGRAM:

Pos.	Time	Event
1.	9:00	Welcome to Day 2 of the Workshop Alexander Treffer, SENTECH Instruments GmbH, Berlin
		Session I: Challenges in Spectroscopic Ellipsometry
2.	9:10	Ellipsometry of Samples with Non-Idealities, including Backside Reflections causing Depolarization Elena Ermilova, SENTECH Instruments GmbH, Berlin
	9:45	Coffe Break
3.	10:15	Exercise: Non-Idealities causing Depolarization
	12:15	Lunch Break
		Session II: Anisotropy
4.	13:35	Mueller Matrix Ellipsometry on Anisotropic Material Systems Sven Peters, SENTECH Instruments GmbH, Berlin
5.	14:05	Exercise: Mueller Matrix Ellipsometry
	15:10	Coffee Break
6.	15:30	Practical Workshop - Live Measurement of Customer Samples
	17:00	End of Workshop – Day 2